



Transaction Information

Tool ID	
Tool Status	Connected
Location	
Wafer Size	300 mm
Fab Section	Etch
Tool Available Date	

General Product Information

Vendor Supplier	TEL
Model	TEL TACTRAS with VIGUS Ix BSP Chambers
Vintage	
Serial No	
Asset Description	Reactive Ion Etcher
Software Version	Ver. 6.80
CIM	GEM
Process	MHM Trench

Hardware Configuration

System Type	Description	Quantity
Options System	Nitrogen Purge Storage and Controller	1
Factory Interface	FOUP	3
Handler System	Loader Module YASKAWA Model (XU-RC845M-C00)	1
Main System	VIGUS Ix BSP Chamber	6
Others		

Excluded Items List (Pumps, Chillers & Abatement are all excluded)

Description	Quantity
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Description	Quantity
TM Robot Controller	1
PM1 TMP Controller	1
PM1 Lifter Pin Driver	1